Alloyed β -(Al_xGa_{1-x})₂O₃ Bulk Czochralski Single β -(Al_{0.1}Ga_{0.9})₂O₃ and Polycrystals β -(Al_{0.33}Ga_{0.66})₂O₃, β -(Al_{0.5}Ga_{0.5})₂O₃) and Property Trends

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Abstract

In this work, bulk Czochralski-grown single crystals of 10 mol.% Al₂O₃ alloyed β -Ga₂O₃ – monoclinic 10% AGO or β -(Al_{0.1}Ga_{0.9})₂O₃ – are obtained, which show +0.20 eV increase in the bandgap compared to unintentionally doped β -Ga₂O₃. Further, growths of 33% AGO – β -(Al_{0.33}Ga_{0.67})₂O₃ – and 50% AGO – β -(Al_{0.5}Ga_{0.5})₂O₃ or β -AlGaO₃ – produce polycrystalline single-phase monoclinic material (β -AGO). All three compositions are investigated by X-ray diffraction (XRD), Raman spectroscopy, optical absorption, and ²⁷Al nuclear magnetic resonance (NMR). By investigating single phase β -AGO over a large range of Al₂O₃ concentration (10-50 mol.%), broad trends in lattice parameter, vibrational modes, optical band gap, and crystallographic site preference are determined. All lattice parameters show a linear trend with Al incorporation. According to NMR, aluminum incorporates on both crystallographic sites of β- Ga_2O_3 , with a slight preference for the octahedral (Ga_{II}) site, which becomes more disordered with increasing Al. Single crystals of 10% AGO were also characterized by X-ray rocking curve, transmission electron microscopy, purity (glow discharge mass spectroscopy, X-ray fluorescence), optical transmission $(200 \text{ nm} - 20 \mu\text{m} \text{ wavelengths})$, and resistivity. These measurements suggest that electrical compensation by impurity acceptor doping is not the likely explanation for high resistivity, but rather the shift of a hydrogen level from a shallow donor to a deep acceptor due to Al alloying. Bulk crystals of β -(Al_{0.1}Ga_{0.9})₂O₃ have the potential to be ultra-wide bandgap substrates for thin film growth, with a lattice parameter that may even allow higher Al concentration β -Ga₂O₃ single crystal thin films to be grown.

I. Introduction

Ultra-wide bandgap β-(Al_xGa_{1-x})₂O₃ (AGO) alloyed bulk substrates are needed to improve lattice matching for thin film growth of high alumina β-Ga₂O₃ by techniques such as molecular beam epitaxy (MBE) and metalorganic chemical vapor deposition (MOCVD). Rapid development of β-Ga₂O₃ materials and devices is possible due to readily available bulk material grown by techniques such as Czochralski, vertical gradient freeze (VGF), edge-defined film-fed growth (EFG), vertical Bridgman, and float zone techniques.¹⁻⁴ The monoclinic phase of alumina, θ -Al₂O₃, is predicted to have a bandgap of 7.24 eV,^{5,6} compared to β-Ga₂O₃ (4.5 – 4.9 eV).⁷ The larger bandgap of AGO materials would enable higher critical field devices^{8,9} and electronics for deeper in the ultraviolet.^{10,11} Further, *n*-type doping (e.g., Si, Zr, Hf) is still possible in AGO material,¹² and has been reported for thin films.^{13,14} Modulation-doped twodimensional electron gas AGO/Ga₂O₃ devices with silicon delta doping are critical for improving mobility and scaling up for high performance transistors.¹⁵⁻²²

Epitaxial growth of β -(Al_xGa_{1-x})₂O₃ (AGO) has been explored using MBE,²³ and MOCVD.^{14,22} Kaun *et al.* reported that the monoclinic phase stability limit of Al₂O₃ in β -Ga₂O₃ (010) at 600 °C growth by MBE was less than ~18%.²⁴ Higher aluminum incorporation is reported in MOCVD growth, with the maximum aluminum incorporation dependent on the growth orientation. Higher Al incorporation was observed in AGO films grown on (100)²⁵ and (-201)²⁶ substrates, compared to (010) orientation,^{14,22} with a maximum Al of 52% on the metal site.

Bulk CZ grown crystals of AGO have been synthesized previously at doping concentrations up to 5 mol.% Al₂O₃ β -(Al_{0.05}Ga_{0.95})₂O₃ with demonstrated 0.11 eV increase in the bandgap from β -Ga₂O₃.²⁷ Additions of low concentration of Al₂O₃ had a negligible effect on melting temperature, only 16 K higher than unintentionally doped (UID) β -Ga₂O₃.²⁷ Alloying with alumina also reduced the decomposition of the melt at growth temperatures.²⁷ AGO has also been studied during co-doping experiments with Ce + Si in order to increase the bandgap and improve scintillation by tailoring *n*-type conduction.²⁸ The optical floating zone method has been used to grow AGO up to β -(Al_{0.15}Ga_{0.85})₂O₃, with the purpose of increased

X-ray scintillation through increasing the bandgap.²⁹ Grown by Li *et al.*, these crystals achieve good detector performance, which is attributed to their materials' insulating properties and high quality of the grown crystal. Recent work on CZ grown crystals has increased the Al concentration further, up to β -(Al_{0.182}Ga_{0.818})₂O₃ (described in Ref³⁰ as 7.5 at% Al by energy dispersive spectroscopy (EDS), but identical to x = 0.182 as shown in Ref³¹) and most recently β -(Al_{0.23}Ga_{0.77})₂O₃ (9.2 at% Al by EDS),³¹ though CZ crystals with even x = 0.062 show evidence of polycrystallinity from X-ray rocking curve measurements.³¹ Crystals of Ga₂O₃ alloyed with higher Al₂O₃ fraction grown by Czochralski have not been reported to our knowledge.

In the current work, we describe the growth attempts of AGO with Al₂O₃ contents from 10-50 mol.%. The intent of the described study is to report the trends in structural and spectroscopic properties of high-Al₂O₃ AGO, which may be polycrystalline, as compared to lower-Al₂O₃ AGO which shows bulk single crystallinity. Here we report successful synthesis of β -(Al_xGa_{1-x})₂O₃ bulk single crystals by the Czochralski technique, at *x* = 0.1 (10% Al₂O₃, hereafter referred to as 10% Al AGO), and further studies on growths where bulk single crystals were not obtained, for compositions where *x* = 0.5 (50% Al₂O₃) and 0.33 (33% Al₂O₃). 10% Al on the metal sites of β -Ga₂O₃ yielded bulk single crystals of sizes sufficient to act as substrates for thin film growth while increasing the bandgap appreciably, and demonstrated several orders of magnitude higher resistivity than UID material. Comparison of the three compositions allowed insight into structural changes with increasing Al₂O₃ addition, including the dependency of the lattice parameters of the monoclinic phase on Al₂O₃ concentration. Nuclear magnetic resonance (NMR) indicated Al incorporation on both the octahedral (Ga_{II}) and tetrahedral (Ga_I) sites, with a preference for the Ga_{II} site for all compositions. XRD and Raman measurements show clear trends associated with Al incorporation into β -Ga₂O₃.

II. Methods

Growths of β -(Al_xGa_{1-x})₂O₃, where x = 0.5, 0.33, 0.1, were performed from the melt with methods similar to those previously published.^{32–34} High purity precursor powders – 5N (99.999%) Ga₂O₃ (ABSCO Limited, Haverhill, Suffolk, UK) and 4N7 (99.997%) Al₂O₃ (Inframat Adv. Mat., Manchester, Connecticut, USA) – were batched and mixed for 18 hours at 50 rpm in a rotary mill. Two charges of ≈425 g were prepared, cold pressed at 140 MPa, and calcined in an alumina crucible with Pt foil lining at 1600°C or 1500°C in air for 15 h. In preparation of the 50 mol.% Al₂O₃ and 33 mol.% Al₂O₃ growths, 1500°C calcines were used, which did not sufficiently sinter the charge due to the addition of alumina, thus for 10 mol.% Al_2O_3 a 1600°C calcine was conducted which sintered the charge properly. The first charge was melted and cooled with material loss of ≈ 17 g due to evaporation, and then the second charge was added with a total AGO material weight of \approx 833 g. The growths were conducted in an iridium crucible (Johnson Matthey, London, UK) with a 70 mm diameter, 70 mm height, 2 mm wall thickness and 3 mm bottom thickness, inductively coupled to a radio frequency (RF) coil. The crucible was rotated at 2 rpm for the duration of the run, with no rotation of the seed. Standard oxygen flow scheme for Ga_2O_3 was employed to reduce decomposition of the melt, following the work by Galazka et al.,^{1,35} in which a mixed gas of Ar+10 vol.% O_2 was used when the melt was at growth temperatures; otherwise when > 1100°C, the gas environment was Ar+2.5-3.5 vol.% O₂, and at < 1100°C, O₂ < 0.2 vol.% was used. During growth, a 10 – 20 kPa overpressure was maintained. Temperatures were monitored during growth using two pyrometers, an Ircon 2 channel pyrometer, and a Sekidenko OR1000F pyrometer, and these measurements demonstrated good agreement in temperature throughout the run. Precise temperature measurement of the growths has been described elsewhere.³³

At ≈ 1850 °C, crystals were grown by CZ at 2 mm/h pull rate and 2 rpm rotation, and subsequently by VGF with no rotation upon cooling at 1-2 °C min⁻¹. Non-spiral 10% Al AGO CZ crystals were grown on a Mg-doped β -Ga₂O₃ seed, with the boule exhibiting a diameter of 41.5 – 36.6 mm and a cylindrical height of 14.5 mm. The height from tip to heel was 22.4 mm. 50% and 33% Al AGO growths did not yield successful CZ crystals, with the pulled CZ mass and most of the VGF being highly polycrystalline.

For single crystalline samples of 10% Al AGO, (100)-oriented crystals of size of 0.25×0.25 cm² to 1×1 cm² with varying thicknesses were obtained from the VGF and CZ growths. 33% AGO had very poor single crystalline quality, yielding only a few samples large enough to be tested, while the rest were polycrystalline. Polycrystalline material was obtained from the VGF boule of the 50% Al and 33% Al AGO and ground up for measurements. The material was single phase for all growths as confirmed by XRD (see Results). Polycrystalline growths were opaque and white in color. 10% Al VGF crystals were greyer than comparable UID β -Ga₂O₃. The 10% Al CZ pulled crystal was beige in color, similar to our UID β -Ga₂O₃.

High resolution High Angle Annular Dark Field-scanning transmission electron microscopy (HAADF-STEM) imaging and electron diffraction were carried out on the 10% Al AGO using a FEI Titan G2 60-300 transmission electron microscope (TEM) operated at 300 kV. A condenser aperture of 70 μm was used with a corresponding convergence angle of 30 mrads and the inner and outer annular detector collection semi-angles equal to 42 and 244 mrad, respectively. The probe current was approximately 90 pA. Camera length for both imaging and diffraction was set to 115 mm. Diffraction pattern indexing was done with the help of SingleCrystal.

Phase purity and lattice parameters were analyzed for all compositions with an X-ray diffractometer (XRD) using Cu K_a radiation ($\lambda = 1.5406$ Å), either Panalytical X'pert Pro at 45 kV and 40 mA (UID, 10% AGO, 33% Al AGO), or a Rigaku Miniflex 600 at 40 kV and 15 mA (50% Al AGO). In all cases, scans were performed from 5-90° 20 with a step size of 0.5° and 10 s per step. Final XRD patterns were obtained from summation of five sequential scans. Rietveld refinement was conducted in HighScore Plus (Malvern Panalytical) software with custom refinement parameters. High resolution rocking curve measurements were collected on 10% Al AGO with a 4-bounce Ge (220) monochromator and a PiXCEL3D (Malvern Panalytical) X-ray detector using the (400) reflection and 45 kV and 40 mA settings, and 1 mm receiving slit size.

Single resonance ²⁷Al magic angle spinning nuclear magnetic resonance (MAS NMR) spectra were recorded on a 14.1 T Varian DD2 600 MHz spectrometer using a commercial 4.0 mm MAS NMR probe (Agilent). All compositions were powdered then packed into 4.0 mm zirconia rotors and spun at 15 kHz. The spectra were measured at 156.27 MHz resonance frequencies with π /6-pulse durations of 0.8-1.2 µs and recycle delays of 2-16 seconds. Measurements were signal-averaged over at least 150 scans and were processed without additional line broadening. Chemical shifts of ²⁷Al were reported relative to powdered AlPO₄, measured at 40.7 ppm relative to 1 M Al(NO₃)₃ at 0 ppm. The spectra were fitted using CZSimple models in DMFit software to simulate the quadrupolar lineshapes observed and quantify the Al site preference.³⁶

Raman shift and peak broadening was studied using a Raman microscope; for all samples, a Thermo Fisher DXR2XI with a 532 nm laser and a grating with a Raman shift range of 100 - 3500 cm⁻¹ with a 2 cm⁻¹ resolution was used. All samples were (100), although orientation of the 50% Al AGO sample could not be assessed due to the polycrystallinity of the sample. Laser intensity as well as exposure was kept the same between measurements. All measurements are composed of 5 spectra which are then averaged to reduce noise.

Sample purity and aluminum concentration were assessed only on 10% Al AGO, using both glow discharge mass spectroscopy (GDMS) and X-ray fluorescence (XRF) at EAG Laboratory (California, USA). Samples were taken from both the VGF and CZ portions of this growth. GDMS was performed on 10% Al AGO after the crystals were crushed in an alumina mill, while XRF was only performed after crushing in a tungsten carbide mill to verify the incorporation of Al without potential Al contamination. The results summarized in the supplementary material show elements at concentrations above the detection limit, of note an as-expected Al incorporation, and lower than typical incorporation of key acceptors and donors (e.g., in the CZ, Fe: 1×10^{17} cm⁻³, Si: 1×10^{18} cm⁻³).

Room temperature optical transmission measurements in the ultraviolet-visible-near infrared (UV-Vis-NIR) and infrared (IR) were conducted on $160 - 180 \mu m$ or 3 mm thick single crystal windows, respectively. Band edge measurements for 10% Al AGO windows were obtained using a Cary 5 UV-VisNIR, for 200 - 3300 nm (50,000 - 3,333 cm⁻¹) using a polarizer to obtain transmission for E||b and E||c. IR measurements were obtained using a Bruker Alpha Fourier transformed infrared (FTIR) spectrometer, for $1.3 - 25.0 \mu m$ (7,500 - 400 cm⁻¹). FTIR spectra were taken before and after a 15 hour 1000 °C anneal in flowing oxygen where samples were placed in an alumina boat with a platinum liner. Optical transmission and Kubelka-Munk scattering measurements, from 190 - 1100 nm (50,000 - 9,090 cm⁻¹), were also obtained on powder samples to allow assessment of polycrystalline materials, using an integrating sphere in a UV-Vis spectrometer (ThermoFisher Evolution 260 Bio). All optical spectra were analyzed with respect to absorptions due to the band edge, free electron carriers, impurities and multiphonon processes.

For electrical measurements, 50-50% Ga-In ohmic contacts were placed on both sides of the (100) plane of the 10% Al AGO crystal in a two-point configuration. Samples were annealed at 950°C for 15 minutes, and then more contact material was placed on top of the old contact. This procedure has been shown to produce contacts with ohmic behavior down to temperatures as low as ≈ 20 K.³⁴ Two-point through thickness current-voltage (*I-V*) and resistance measurements were obtained with a high impedance picoammeter.

III. Results and Discussion

A. Growth

Bulk CZ growth of 10% Al AGO (i.e., β -(Al_{0.1}Ga_{0.9})₂O₃ or β -Al_{0.2}Ga_{1.8}O₃) demonstrated less melt evaporation than UID β -Ga₂O₃, as expected from previous reports from literature.²⁷ Supercooling of the crystal by approximately 40°C, from 1850°C to 1810°C, was required in order to seed and grow. Phase diagrams of the β -Ga₂O₃ and Al₂O₃ system by Hill *et al.*³⁷ show a region of reduced solubility below 800°C; however, when cooling the crucible and crystals at a rate of 1°C min⁻¹ (specifically at 800°C), 10% Al AGO was realized with no secondary phases.

Obtained crystals are shown in Fig. 1. The CZ boule was asymmetric, although not spiral. Many large grain single crystals separated by grain boundaries and cracks made up the CZ boule, caused by

difficulties in seeding. The lack of an after heater in this growth is also considered deleterious to the quality of the crystal, specifically resulting in cracking and a high vertical temperature gradient. Some inclusions are visible on the outside CZ surface, but morphology is similar to Ir deposits typically seen on other CZ β -Ga₂O₃ growths. There are no visible inclusions through the (100) surface of substrates.

10% Al AGO CZ crystals were measured with XRF and indicated an incorporation of 11.74 mol.% Al₂O₃, resulting in an effective incorporation coefficient, mk_{eff} , of 1.17, agreeing well with literature, where Al is reported having an mk_{eff} of 1.1 in 5 mol.% Al₂O₃ in β -Ga₂O₃.²⁷ There were minor differences in Al concentration between the VGF and CZ boule; however, as shall be shown within this work, the concentrations were such that structural, optical and electronic properties were much the same between the VGF and CZ. Purity data is shown in the supplementary materials.

Polycrystalline growths of 50% Al AGO (i.e., β -(Al_{0.5}Ga_{0.5})₂O₃ or β -AlGaO₃) and 33% Al AGO (i.e., β -(Al_{0.33}Ga_{0.67})₂O₃ or β -Al_{0.66}Ga_{1.34}O₃) were obtained on a sapphire seed and an Ir rod, respectively, as seeding with Mg: β -Ga₂O₃ was unsuccessful due to seed melting. The resultant pulled crystals were polycrystalline and not cylindrical. VGF growth of 50% Al AGO yielded columnar structures throughout the boule, with no single crystals of appreciable size. 33% Al AGO yielded some very small single crystals with poor surface quality consisting of many cracks and uneven surfaces, but otherwise was a mass of polycrystalline material.



FIG. 1. a) 10% Al AGO CZ pulled crystal. b) 10% Al AGO VGF boule in iridium crucible. c) As-grown chunk of single crystal from the CZ boule. d) As-grown chunk of single crystal from the VGF boule with clearly rough surface. e) 33% Al AGO CZ pulled crystal seeded on Ir rod and VGF boule. f) 50% Al AGO VGF boule with various core drill holes in the surface. Note metallic spot near center of boule, most likely Ir.

B. Structural Properties

In order to assess crystal quality in terms of lattice defects, second phases, and Al incorporation,

several techniques were applied to AGO samples.

HAADF-STEM was applied in order to assess defects and crystal quality of the 10% Al AGO crystals. Images (Fig. 2) of the investigated area indicate a well-ordered lattice with no visible structural defects, and successful Al incorporation onto both octahedral and tetrahedral sites in the expected monoclinic crystal structure.



FIG 2. a) High resolution High angle annular dark field-scanning transmission electron microscopy (HAADF-STEM) image of 10% Al AGO in the $[00\overline{1}]$ projection. The top of the image corresponds to the different carbon coating and protective layers. b) Zoomed-in image of area highlighted by the red square in Fig 2.a). c) Low magnification TEM image of the sample in the $[00\overline{1}]$ projection and its corresponding diffraction pattern is shown in d). These different TEM techniques show the high quality and single crystallinity of the sample.

High resolution XRD rocking curve measurements on as-grown and as-cleaved UID and 10% Al AGO samples demonstrate crystal quality expected from Czochralski grown single crystals (Fig. 3). Only one sample was measured from each boule, although attempts were made to select from the regions representative of the measurements presented herein. Industrially grown β -Ga₂O₃ EFG substrates, for example, are certified for \leq 150 arcsec (Novel Crystal Technologies, Inc.). A (010) Fe-doped β -Ga₂O₃ substrate obtained from industry and grown via CZ was measured with the same XRD system and

demonstrated ≈ 105 arcsec. Research-grade β -Ga₂O₃ crystals have shown 17 arcsec (EFG),³ 10 – 50 arcsec (vertical Bridgman),³⁸ and 23 – 36 arcsec (Czochralski).³⁵ Previous reports of β -(Al_{0.0625}Ga_{0.9375})₂O₃ via CZ showed lower quality crystals at lower Al concentration with split diffraction peaks, and although higher Al concentration (x = 0.23) was reported, rocking curve was not shown.³¹ Of note in Fig. 3 is the sideband right of the primary peak, as well as general asymmetry of the peaks. This is caused by the cleavage planes or cracking in β -Ga₂O₃ which cause mosaic-like or platelet-like surface morphology at large length scales, or the presence of low angle grains and twin boundaries in the crystal.



FIG 3. High resolution rocking curve XRD measurement of (100) oriented AGO 10% and UID. Receiving slit on PiXCEL3D was 1 mm.

Powder XRD was used to study lattice behavior as a function of aluminum content. As aluminum concentration increases, a shift to higher 2θ angles is noticeable in the patterns, attributed to shrinking of the lattice (Fig. 4a,b). In order to assess whether second phases were forming, XRD was applied to material obtained from the top and bottom of the crucible, and from all AGO concentrations attempted, and no significant differences (other than shifts) between the patterns were found nor matched any suspected phases (Al₂O₃ or contaminants) in the XRD libraries. Several peaks change in intensity as a function of

AGO concentration: 62.7° 20 increased and 27.1° 20 decreased with increasing Al content. These peaks were matched to the expected monoclinic β -Ga₂O₃ structure, and are most likely indicative of disorder within the crystal especially at high Al concentration. Measurements on all of the alloys demonstrated patterns with peaks identifiable by the UID β -Ga₂O₃ structure, indicating the alloys formed solid solutions with no second phases. A higher resolution plot of Fig. 4b may be found in the supplementary. Due to the availability of high Al concentration single phase polycrystals at *x* = 0.33 and *x* = 0.50, the authors were able to study the crystal lattice as a function of alloying. Lattice parameters were obtained via Rietveld refinement (Fig. 4c), with a linear decrease in lattice size as expected based on 20 shift. These trends suggest that future studies could use lattice parameters to directly obtain the Al concentration on material with an unknown *x* using the fitted equations presented here. This would allow for a benchtop approximation of *x*, complementary to other techniques such as energy dispersive spectroscopy (EDS) or X-ray fluorescence (XRF).



FIG 4. a) XRD patterns of UID vs. AGO, for a region where the peak shift is evident. b) XRD patterns of UID vs. AGO. All spectra in a,b) have been offset for clarity. c) Lattice parameters as a function of Al_2O_3 doping. Lines shown are linear fits to the data.

²⁷Al MAS NMR spectra were collected to investigate the site preference of Al in β-Ga₂O₃ as a function of aluminum content. It is observed in Fig. 5 that each sample contains Al in both tetrahedral (Al-4; centered near 68 ppm) and octahedral (Al-6; centered near 9-12 ppm) sites. Samples were fitted using three distinct peaks within the Al-4 resonance and one to three distinct peaks within the Al-6 resonance (complete fitting parameters provided in Table S1). Area integration of the fitted quadrupolar lineshapes produces site fractions for each sample studied, indicating that AGO with 10% Al (CZ and VGF), 33% Al, or 50% Al all contain a majority of Al in the octahedral (Ga_{II}) site, as is similar to the observations by Cook *et al.*,³⁹ with the area fractions 64%, 71%, and 62%, respectively. Further, we observe insignificant differences in Al-6 fraction between the AGO 10% Al CZ and VGF samples (64% vs. 63% Al-6),

considering that $\pm 1\%$ error is typically assessed to quantifying site fractions in MAS NMR. Notably, the Al-6 resonance of the NMR spectra of 33% Al AGO and 50% Al AGO appear significantly broadened and shifted upfield as compared to the 10% Al AGO samples, and the former samples were satisfactorily fitted using one broad peak, while the latter had to be fit using three distinct peaks. The broadening of the Al-6 peak is attributed to a more disordered octahedral Al site in the higher Al-doped samples; this is confirmed by the increasing value of the quadrupolar coupling constant with increasing Al (see Table S1). The results show that Al prefers to enter the Ga_{II} (octahedral) site but also enters the Ga_I (tetrahedral) site to a significant extent, and that with increased Al concentration, the average octahedral site containing Al becomes more disordered. These results are in agreement with work conducted on thin films, showing similar incorporation behavior.⁴⁰



FIG 5. ²⁷Al MAS NMR spectra of AGO samples. Spectra were fitted using CZSimple functions in DMFit software to fit the quadrupolar lineshapes.

Raman spectroscopy also evidenced a decrease in the lattice volume as scattering shifted to higher wavenumbers with increasing Al concentration (Fig. 6). The Raman scattering shift from UID to 50% Al AGO was 35-40 cm⁻¹. Broadening of Raman peaks indicated more structural disorder as Al content increased. Assignment of Raman modes was performed based on Onuma *et al.*⁴¹ Severe broadening occurred at 50% Al AGO, where several peaks merged (Bg(5), Ag(8), Ag(9): 600 – 700 cm⁻¹), became shoulders (Bg(2), Ag(2), Ag(3): 150 – 200 cm⁻¹), or broadened into the background (Bg(4), Ag(6), Ag(7): 400 – 500 cm⁻¹). Bulk second phases would appear as new peaks or features, which were not present in data taken over several representative samples. Specifically, these spectra are distinct from Al₂O₃ Raman spectra, for example found in the RUFF Raman library⁴² and thus are indicative of AGO remaining in the monoclinic β -Ga₂O₃ structure rather than a change to the corundum, which was also verified by XRD.



FIG 6. 532 nm unpolarized Raman spectra taken with the same laser power and exposure with Raman modes assigned, indicating an increase in disorder and shrinking of the lattice as a function of Al concentration. Plots were offset in the y-axis only for ease of viewing.

C. Optical Properties

Aluminum concentration caused an increase in the apparent bandgap of β -Ga₂O₃ (Fig. 8), as also shown in literature.^{5,27–29,43} Free carrier absorption was notably absent in aluminum alloyed material compared to UID β -Ga₂O₃ grown by the same method, which shows free carrier absorption from unintentional shallow donor impurities (Fig. 7), in agreement with previous studies on Al doping in β -Ga₂O₃.²⁹ This lack of free carrier absorption indicates that the samples are insulating, with near infrared spectra similar to those seen in acceptor-doped insulating crystals.³³ There was a distinct lack of Ir⁴⁺ related absorptions generally seen near the bandedge in insulating materials such as Zn- or Mg-doped β -Ga₂O₃,⁴⁴ indicating in these AGO samples the Fermi level may still be above mid-gap. There were no notable differences between VGF and CZ grown transmission measurements in 10% Al AGO.



FIG 7. Transmission of 10% Al AGO and UID β -Ga₂O₃ samples, both approximately 1.5 mm thick, indicating lack of free carrier absorption in 10% Al AGO. An apparent absorption most notable in AGO 10% but also in UID at \approx 350 nm was due to detector changeover, and is not a real feature.

Tauc analysis was used to quantitatively assess the shift in optical bandgap, E_{opt} , with the equation

(1) used to calculate the absorption coefficient and the Tauc equation (2) for the bandgap.

$$\alpha = \frac{l}{L_1} \times ln \left[\frac{\frac{(1-R)^2 \times 100}{2}}{T_1} + \sqrt{R^2 + \frac{\frac{(1-R)^4}{4}}{(T_1/100)^2}} \right]$$
(1)

$$(\alpha h\nu)^{\bar{\gamma}} = B(h\nu - E_{opt}) \tag{2}$$

1

where the absorption coefficient α is determined from the transmission, the thickness, and calculated reflectance as determined by the refractive index (assumed to be identical to β -Ga₂O₃).⁴⁵ For the Tauc plot, γ is a constant with a value of 0.5 for a direct bandgap, or 2 for an indirect bandgap. β -Ga₂O₃ is a material with a small (0.05 eV) difference between direct and indirect bandgap,^{46,47} such that it can be treated as a direct bandgap,^{47,48} thus 0.5 was selected as the value for γ . Analysis revealed a ΔE_{opt} +0.20 eV from UID to 10% Al AGO, which presented an E_{opt} of \approx 4.99 eV (Fig. 7). Polarization-dependent absorption as light is polarized parallel to the *b* or *c* planes was also observed; analysis of UID samples revealed an apparent bandgap of 4.51 eV and 4.79 eV for measurements polarization parallel to *c* and *b* respectively, and AGO demonstrates a bandgap of 4.79 eV and 4.99 eV for polarization parallel to *c* and *b* respectively. There were no appreciable differences in E_{opt} between VGF and CZ 10% Al AGO samples. Comparison to theoretical work indicates such a ΔE_{opt} would occur with approximately 10 at.% Al content, verifying the alloying content present in the crystals.^{5,49} Note that the measured apparent band gap for UID β -Ga₂O₃ is slightly low compared to theoretical, which is not surprising since even at \approx 150 µm thick samples there is still some contribution from the Urbach tail absorption.



FIG. 8: Tauc plot of UID and 10% Al AGO, showing a $\Delta E_{opt} \sim 0.20 \text{ eV}$.

In order to compare band edge behavior between all AGO materials regardless of crystallinity, powder UV-Vis was also collected with an integrating sphere (Fig. 9). All three alloy concentrations show the optical band edge noticeably shifted from UID β -Ga₂O₃, shown in Fig. 9b. Powder UV-Vis transmittance data was transformed into Kubelka-Munk data, and Equation 3 and further analysis⁵⁰ was applied to study the bandgap,

$$(F(R_{\infty}) \times hv)^{\frac{1}{\gamma}} = B(hv - E_{opt})$$
(3)

where $F(R_{\infty})$ is the Kubelka-Munk function, and the other variables are as described previously for equation (2). The ΔE_{opt} between UID and 10% Al AGO from Kubelka-Munk Tauc plot was +0.19 eV,

whereas window Tauc plot was +0.20 eV. It is notable that bandgap bowing as a function of alumina concentration is seemingly observed in Figure 9b and 9c, which has been shown previously in theoretical work.⁵ Bowing in this case was primarily of the conduction band edge and thus affects shallow donor behavior, since the valence band is still very flat and is not conducive to *p*-type behavior.⁵ The bowing parameters *b* were obtained from Equation 4, where $E_{opt}[Ga_2O_3]$ was the experimentally measured 4.52 eV and $E_{opt}[Al_2O_3]$ in either direct or indirect gap is obtained from Peelaers *et al.*⁵ Bowing parameters calculated from Kubelka-Munk powder UV-Vis data were found to be 2.16 ± 0.16 eV if Al₂O₃ was direct and 1.69 ± 0.15 eV if Al₂O₃ was indirect. Calculations done by Peelaers *et al.* showed bowing parameters of 1.78 – 1.87 eV,⁵ while thin film literature suggested broader results: 1.3,⁵¹ 1.25⁵² and 0.4 eV⁵³ have all been reported.

$$E_{opt}(x) = (1-x)E_{opt}[Ga_2O_3] + xE_{opt}[Al_2O_3] - bx(1-x)$$
(4)



FIG 9. a) Powder UV-Vis demonstrating a shift in the band edge as a function of alumina content. Transmittance has been artificially normalized to the band edge absorption peak for easier comparison. b) Kubelka-Munk Tauc plot powder samples shown in a). c) Kubelka-Munk powder UV-Vis and Window UV-Vis bandgap as a function of Al concentration. Line shown is a quadratic fit to Kubelka-Munk data.

FTIR transmission measurements (Fig. 10) showed similar characteristics to β-Ga₂O₃ studied previously;³³ however, crystals showed a distinct lack of the \approx 5155 cm⁻¹ Ir⁴⁺ absorption peak related to 6-coordinated Ir_{Ga},⁴⁴ which was found in material with a low Fermi level and thus lack of Ir³⁺. Typically acceptor doped (e.g., Mg, Fe, and Zn) β-Ga₂O₃ demonstrated this Ir⁴⁺ absorption peak.^{33,44} 10% Al AGO showed a lack of free carrier concentration, which initially implied a low Fermi level, acceptor doping, and thus Ir⁴⁺ formation; however, several samples were measured with FTIR across the VGF and CZ boule and

all demonstrated a lack of the Ir^{4+} peak. This indicated that the more insulating behavior of AGO (Fig. 10) was *not* due to an increase in acceptors deep in the gap – otherwise the Ir^{4+} absorption would intensify, but instead the widening of the bandgap and deepening of shallow donor states near the conduction band edge was suggested.



FIG 10. FTIR transmission on as-grown and annealed 10% Al AGO, inset showing Ir absorption region and UID, acceptor (Zn) doped, and AGO in that region.

D. Electrical Properties

Resistivity of 50% Al AGO samples were not measured due to lack of single crystalline material. Only one sample of 33% Al AGO was measured, which reported $6 \times 10^7 \ \Omega \cdot cm$. 10% Al AGO showed insulating behavior, with an average resistivity higher than UID β -Ga₂O₃ (Fig. 11), which is also supported by a definitive lack of free carrier absorption in the near infrared (Fig. 7). These results were similar to those published by Li *et al.*, in which their optical floating zone grown 15% Al AGO was reported to have a resistivity of $1.5 \times 10^{12} \ \Omega \cdot cm$.²⁹ This was most likely due to the raising of the conduction band minimum which converted the typical shallow donor impurities to deeper states,¹² equating to a lowering of the Fermi level. Further, Si concentration between UID crystals and AGO was similar, both being on the order of 10^{18} atoms cm⁻³, and with no appreciably large acceptor concentration in AGO. While Si was been shown by Varley¹² to remain an *n*-type shallow donor until much higher Al concentrations (>80% Al), it was been recently shown that shallow hydrogen donor states could become deep donors in AGO at Al concentrations as small as 1%.⁵⁴ Specifically, H_i and H₀ could become deep centers, and compensate the Si donor impurity. The work by Mu *et al.* also discussed complexes of H with Si and C; however these were either unstable or were only acceptors at > 56% Al AGO.⁵⁴ Typically, the Si impurity in β -Ga₂O₃ materials was 10¹⁷ – 10¹⁸ atoms cm⁻³, with Fe at similar concentrations; not much hydrogen would be needed to cause insulating behavior. Hydrogen may have seemed like a trace, or background impurity, but it was shown experimentally that in UID β -Ga₂O₃, hydrogen's contribution to free carrier concentration could be significant and was omnipresent in Czochralski grown crystals,⁵⁵ and thus the deepening of these shallow states could lead to insulating behavior.

The presence of hydrogen is ubiquitous due to the nature of Czochralski growth; the growth chamber is typically not well sealed especially to the small atom of hydrogen, and hydrogen can infiltrate into the source powder, insulation, or the chamber at many stages of growth preparation. An alternative explanation to the increased resistivity is a higher oxygen content in the melt environment due to inclusion of Al₂O₃, which is typically oxygen poor and supplemented by the gas flow scheme.^{1,35} Such an oxygen rich environment would reduce the amount of oxygen related point defects, and potentially cause insulating behavior.



FIG 11. Resistivity of 10% Al AGO and UID. Individual data points shown. For the statistics, the horizontal line in the box is the median, the small inner box is the mean, the colored box represents the 75%/25% interquartile range, and the short horizontal lines the 95%/5% range.

IV. Conclusion

Successful single crystal growth and incorporation of 10 mol.% Al₂O₃ in AGO (i.e., monoclinic β -(Al_{0.1}Ga_{0.9})₂O₃ or β -Al_{0.2}Ga_{1.8}O₃) has been demonstrated, as well as single phase polycrystalline growth of 33 AGO (i.e., monoclinic β -(Al_{0.33}Ga_{0.67})₂O₃ or β -Al_{0.66}Ga_{1.34}O₃) and 50 mol.% AGO (i.e., monoclinic β -(Al_{0.5}Ga_{0.5})₂O₃ or β -AlGaO₃). A β -Ga₂O₃+0.20 eV increase of the optical bandgap was demonstrated for β -(Al_{0.1}Ga_{0.9})₂O₃ from, to 4.99 eV. Crystal quality of 10% Al AGO is comparable to previously grown β -AGO, although somewhat lower quality than literature results for UID crystals, as shown by HAADF-STEM and high resolution rocking curve XRD, and quality could be improved for use as a substrate for thin film. However, we have demonstrated clear trends due to Al addition in β -AGO over a large range of Al₂O₃ (10-50 mol.%). By NMR we show that Al incorporated on both Ga sites, but favored the octahedral site (Ga_{II}), which becomes more disordered as Al content increases. HAADF-STEM further demonstrated Al incorporation onto both crystallographic sites, even for β -(Al_{0.1}Ga_{0.9})₂O₃. Disordering was also implied by the broadening of Raman vibrational bands at higher Al concentrations. The crystal lattice shrank linearly as a function of Al incorporation, as expected from the ionic size, and lattice empirical equations

were generated allowing Al concentration to be estimated from these lattice parameters. Resistivity increased when alloying 10% Al₂O₃ with Ga₂O₃, and free carrier absorption in the near infrared was not observed, presumably due to a widening of the bandgap where normally shallow donors such as hydrogen become deeper states, or else related to a higher oxygen concentration in the melt when Al₂O₃ is introduced.^{12,54} Overall, this study presented optical band gap, lattice parameters, aluminum site distribution, and vibrational spectra for a large range of single phase monoclinic β -AGO (to 50 mol.% Al₂O₃) which should be useful for future researchers.

SUPPLEMENTARY MATERIAL

See the supplementary material for a larger XRD pattern figure, crystal purity data, as well as NMR fitting parameters and calculated site fractions.

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Data Availability Statement

The data that support the findings of this study are available from the corresponding author upon reasonable request.

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